

Electronic Supplementary Material (ESI) for RSC Advances
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Supplementary Information

Solution-processed SiO₂ gate insulator formed at low temperature for zinc oxide thin-film transistors

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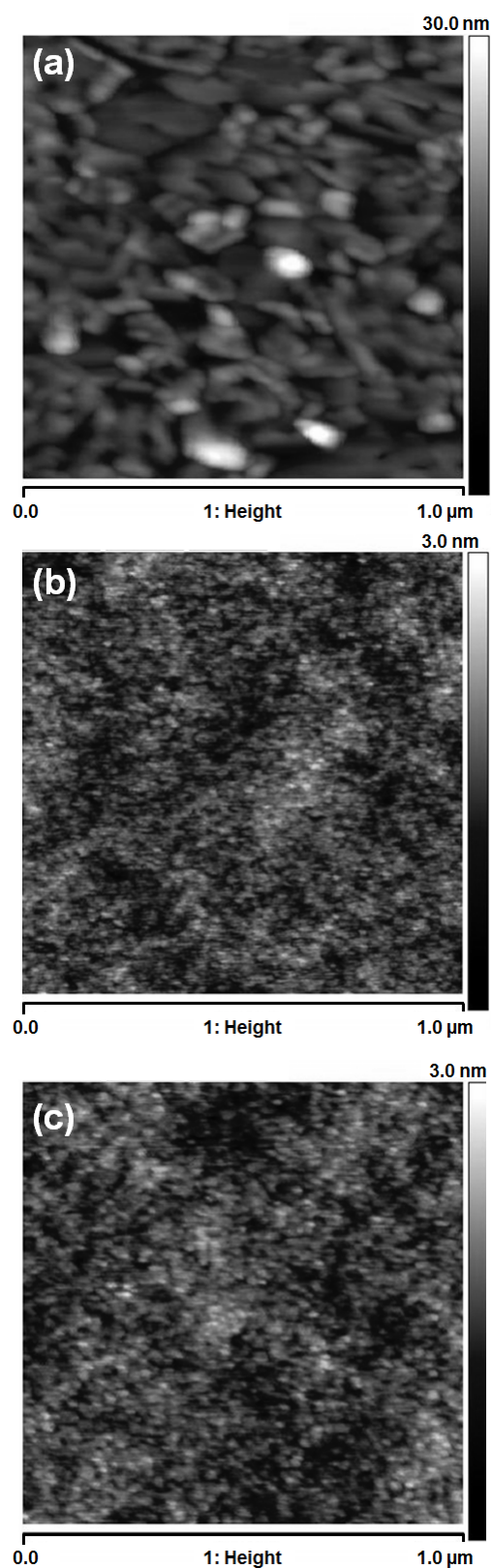


Fig. S1. AFM topography images of (a) evaporated Al (b) PHPS spin-coated onto Al and (c) pre-annealed PHPS film following spin-coating on Al.

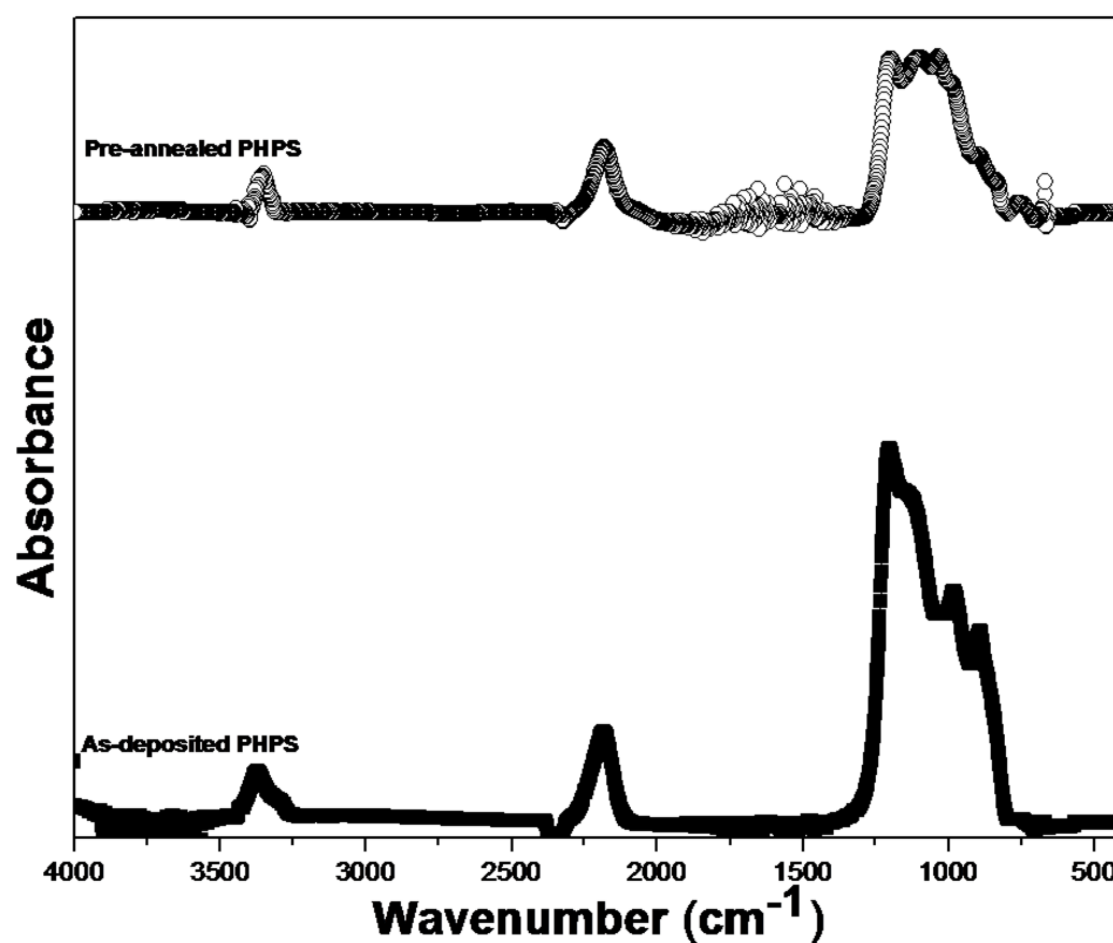


Fig. S2. FTIR spectra of spin coated PHPS before and after pre-annealing. These spectra were recorded using a Nicolet Nexus spectrometer with a liquid nitrogen cooled HgCdTe crystal detector. The background spectrum was measured by collecting 128 scans between 400 cm⁻¹ and 4000cm⁻¹ using an Al coated glass slide.

Group vibration	Wavenumber (cm ⁻¹)
Si-O rock	460
Si-N stretch in Si-N-Si	920,840
Si-O stretch	1060
Si-O-Si stretch	1163
N-H bend	1180
Si-H stretch	2160
N-H stretch	3360

Table. S1. IR peak assignments.¹⁻⁵

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